

Device and method for examining and manipulating microscopic objects

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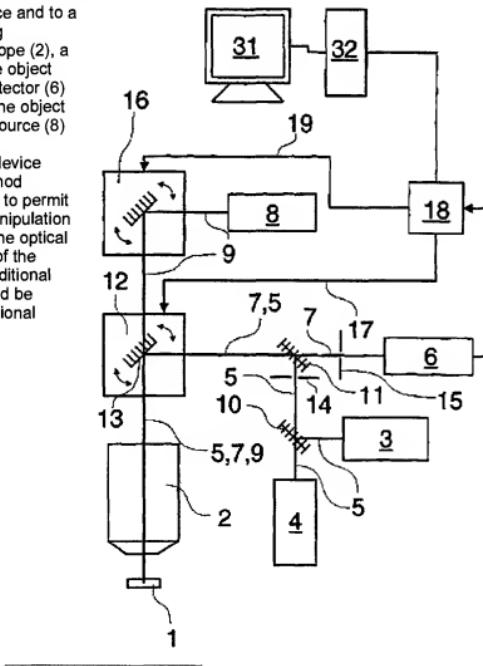
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Abstract not available for DE10039520

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The present Invention relates to a device and to a method for examining and manipulating microscopic objects (1), with a microscope (2), a light source (3, 4) used to illuminate the object (1), an illumination beam path (5), a detector (6) used to detect the light returning from the object (1), a detection beam path (7), a light source (8) used for the object manipulation and a manipulation light beam path (9). The device according to the invention and the method according to the invention are intended to permit three-dimensional examination and manipulation of objects (1) whose dimension along the optical axis is greater than the depth of focus of the microscope objective used, with the additional intention that object manipulation should be possible at all sites of the three-dimensional object (1).



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